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PATENT

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicants : Gaetano Santoruvo et al.
Filed : December 20, 2001
For : HEATING ELEMENT FOR MICROFLUIDIC AND
MICROMECHANICAL APPLICATIONS



Docket No. : 01-RB-075 (850063.587)
Date : December 20, 2001

Box Patent Application
Commissioner for Patents
Washington, DC 20231

INFORMATION DISCLOSURE STATEMENT

Commissioner for Patents:

In accordance with 37 C.F.R. §§ 1.56 and 1.97 through 1.98, applicants wish to make known to the Patent and Trademark Office the references set forth on the attached form PTO-1449 (copies of the cited references are enclosed). Applicants wish to disclose and have officially considered the following co-pending applications: Application entitled Thin Film Transistor used as Heating Element for Microreaction Chamber, filed December 20, 2001, Docket No. 01-C-120 (850063.589); Application No. 09/779,980, filed February 8, 2001, entitled Integrated Device for Microfluid Thermoregulation, and Manufacturing Process Thereof; Application No. 09/874,382, filed June 4, 2001, entitled Process for Manufacturing Integrated Chemical Microreactors of Semiconductor Material; Application No. 09/965,128, filed September 26, 2001, entitled Integrated Chemical Microreactor, Thermally Insulated from Detection Electrodes, and Manufacturing and Operating Methods Therefor. As to any reference supplied, applicants do not admit that it is "prior art" under 35 U.S.C. §§ 102 or 103, and specifically reserve the right to traverse or antedate any such reference, as by a showing under 37

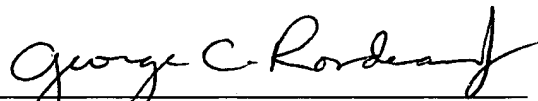
and Trademark Office in compliance with applicants' duty to disclose all information they are aware of which is believed relevant to the examination of the above-identified application, applicants believe that their invention is patentable.

Please acknowledge receipt of this Information Disclosure Statement and kindly make the cited references of record in the above-identified application.

Respectfully submitted,

Gaetano Santoruvo et al.

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Enclosures:

Form PTO-1449

Cited References (12)

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